will give you the Advantage

20F/12



Outline

- -Fully-automatic BG Tape remover for single wafer.
- -After the wafer is aligned, the back grinding tape is UV irradiated as necessary. Then the peeling tape is attached to the wafer periphery by heat seal method, and back grinding tape removal is performed.
- -By using our unique wafer holding table and the new peeling method that reduces stress on the wafer, back grinding tape removal is performed without any contact with the wafer backside.
- -By adopting the non-contact wafer backside handling method, contamination of wafer is prevented.

- Option · Host Communication Function(Communication Format: Conforms to SECS-I and HSMS/Software: Conforms to GEM)
 - ·Compatible with clean room applications, and suitable for front-end process

Suitable Tapes ·BG Tape: Adwill E series, P series

Facility

Power Supply Voltage : AC200-230V ±10%

Frequency

Phase

(AC190-253V) : 50/60Hz : single phase

Power consumption : 3.5kW (with UV Irradiation

System: 10kW)

Air Supply Air pressure

: 0.6-0.8MPa Air consumption : >200L/min (ANR)

Vacuum Supply (for workpiece)

Vacuum pressure : >-80kPa

Applicable Wafer Size 300mm

Please inquire about options for compatibility

with specific wafer sizes.

Width: 1,440mm Size Depth: 2,105mm

Height: 1,800mm

(excluding the signal tower and protruding parts)

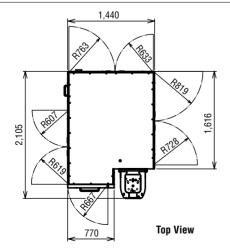
Weight 1,600kg

UPH 45wafers/hour

The above processing capacity is based on following conditions: Wafer : 300mm diameter non-polished mirror wafer

Back grinding tape: E-6142S from LINTEC

External View



1 440 1,800 **Front View Right Side View**

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Unit:mm